



## UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE  
United States Patent and Trademark Office  
Address: COMMISSIONER FOR PATENTS  
P.O. Box 1450  
Alexandria, Virginia 22313-1450  
www.uspto.gov



Bib Data Sheet

CONFIRMATION NO. 6686

|                             |                                       |              |                        |  |
|-----------------------------|---------------------------------------|--------------|------------------------|--|
| SERIAL NUMBER<br>09/530,588 | FILING DATE<br>05/05/2000<br><br>RULE | CLASS<br>438 | GROUP ART UNIT<br>2814 | ATTORNEY<br>DOCKET NO.<br>2312-0866-2P |
|-----------------------------|---------------------------------------|--------------|------------------------|--|

## APPLICANTS

KIMIHIRO MATSUSE, INAGI-SHI, JAPAN;

HAYASHI OTSUKI, NAKAKOMA, JAPAN;

## \*\* CONTINUING DATA \*\*\*\*\*

This application is a 371 of PCT/JP98/04983 11/05/1998

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

JAPAN 9-319059 11/05/1997

JAPAN 10-207198 07/07/1998

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 06/06/2000

|   |                              |                        |                      |                            |
|---|------------------------------|------------------------|----------------------|----------------------------|
| Foreign Priority claimed<br><input type="checkbox"/> yes <input type="checkbox"/> no  | STATE OR<br>COUNTRY<br>JAPAN | SHEETS<br>DRAWING<br>4 | TOTAL<br>CLAIMS<br>8 | INDEPENDENT<br>CLAIMS<br>4 |
| 35 USC 119 (a-d) conditions<br>met <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after<br>Allowance |                              |                        |                      |                            |
| Verified and<br>Acknowledged  | Examiner's Signature         | Initials               |                      |                            |

## ADDRESS

22850

OBLON, SPIVAK, MCCLELLAND, MAIER &amp; NEUSTADT, P.C.

1940 DUKE STREET

ALEXANDRIA, VA

22314

## TITLE

METHOD OF FORMING SEMICONDUCTOR WIRING STRUCTURES.

FILING FEE

FEES: Authority has been given in Paper  
No. \_\_\_\_\_ to charge/credit DEPOSIT ACCOUNT☐ All Fees☐ 1.16 Fees ( Filing )☐ 1.17 Fees ( Processing Ext. of  
time )